

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Miller et al.**

Serial No.: 09/863,979

Filed: May 23, 2001

For: **Method and Apparatus for
Deposition of Porous Silica Dielectrics**§
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Group Art Unit: 1763

Examiner: **Lund, Jeffrie Robert**

Attorney Docket No.: 98-197/1D

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GROUP 1700# 1600E
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I hereby certify this correspondence is being transmitted via
facsimile to the Commissioner for Patents, P.O. Box 1450,
Alexandria, VA 22313-1450, facsimile number (703) 872-
9311, on June 10th, 2003.

By: _____

Amelia C. Neering
Amelia C. NeeringRESPONSE TO FINAL OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

No fees are believed to be required. If, however, any fees are required, I authorize the Commissioner to charge these fees which may be required to LSI Logic Corporation Deposit Account No. 12-2252. No extension of time is believed to be necessary. If, however, an extension of time is required, the extension is requested, and I authorize the Commissioner to charge any fees for this extension to LSI Logic Corporation Deposit Account No. 12-2252.

In response to the Final Office Action dated March 13, 2003, please amend the above-identified application as follows: